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## PATENT APPLICATION

### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q60716

Hiromoto OHNO, et al.

Appln. No.: 10/088,306

Group Art Unit: 3749

Confirmation No.: 2926

Examiner: Kathryn S. O Malley

Filed: March 18, 2002

For: CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT

#### AMENDMENT UNDER 37 C.F.R. § 1.111

##### MAIL STOP AMENDMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Responsive to the outstanding Office Action dated October 19, 2004, please amend the above-identified application as follows.

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